

Federal Institute for Materials Research and Testing

## CERTIFIED REFERENCE MATERIAL BAM-L101

TiO<sub>2</sub>/SiO<sub>2</sub> multilayer on BK7 glass

ausverkauft / out of stock

### Certified quantity:

The batch value for the total layer thickness  $d_t$  of TiO<sub>2</sub>/SiO<sub>2</sub> multilayer coatings on BK7 glass substrates.

Certified quantity	Certified value, nm	Uncertainty, nm k = 2
$d_t$	964	24

### Informative values:

#### *A: Surface topography and roughness*

The roughness in micrometer range was evaluated by white light interference microscopy (WLIM). The area investigated was (70 x 70) μm<sup>2</sup>, the determined statistical roughness values are

roughness average  $R_a = 4.6$  nm, and  
mean roughness depth  $R_z = 53.8$  nm.

#### *B: Single layer thicknesses*

Spectroscopic ellipsometry (SE) was used for the determination of  $d_t$ . Based on a model, individual layer thicknesses of the multilayer stack have been derived. The following table provides these data from layer 1 on the substrate to layer 10 on top of the layer stack.

	layer no										
	1	2	3	4	5	6	7	8	9	10	sum
thickness/ nm	93,6	91,5	92,1	106,2	93,5	92,4	93,7	101,7	91,4	108,4	964,5

#### *C: Optical properties and depth profiling*

In addition, the reference material has been characterised by optical transmission spectroscopy and depth profiling techniques as given in the certification report.

### ***DESCRIPTION OF THE SAMPLE***

TiO<sub>2</sub>/SiO<sub>2</sub> multilayer coatings (5 x TiO<sub>2</sub>/SiO<sub>2</sub>) with nominal individual layer thicknesses of 100 nm and 1 μm nominal total layer thickness have been deposited on polished Schott BK7 glass substrates, squares of (50 x 50) mm<sup>2</sup> size and 1.1 mm thick, using an electron beam evaporation process. The deposition sequence starts with TiO<sub>2</sub> (layer on the substrate) and ends up with SiO<sub>2</sub> (top layer of layer stack). To improve adhesion, the substrate has been coated with a 60 nm SiO<sub>2</sub> inter-layer which is not part of the certified layer system.

### ***INSTRUCTION FOR USE***

TiO<sub>2</sub>/SiO<sub>2</sub> multilayer coatings are intended to be used for the evaluation and calibration of depth measurements and depth resolution of surface analytical methods (e.g. glow discharge optical emission spectroscopy, GD-OES) and for the evaluation and calibration of metallographic preparation methods (e.g. cross-sectioning, ball grinding).

For the batch, a mean value of  $d_t$  valid for the central surface area of a size of (45 x 45) mm<sup>2</sup> was certified. This was done for a surface topography as measured by WLIM.

In case of use, it is a prerequisite to avoid any mechanical (such as scratching) or chemical treatment (such as aggressive agents) of the surface. Storage under ordinary laboratory conditions results in an unavoidable film of adsorbed water of some nanometer thickness that may be considered for evaluation.

### ***ANALYTICAL METHODS USED***

The determination of the certified value was performed by means of a validated and calibrated spectroscopic ellipsometry measurement according to PAS 1022: "Reference Procedure for Determination of Optical and Dielectric Material Properties and Thickness of Thin Films by Ellipsometry", Beuth Verlag Berlin 2004. The certification procedure was conducted in a laboratory of BAM accredited according to DIN EN ISO/IEC 17025 (DAP-PL-2614.08).

### ***DATA EVALUATION***

1. All samples of the batch have been tested non-destructively by means of spectroscopic ellipsometry.
2. For batch reference samples, destructive testing has been performed as well. Preparation method was focused ion beam (FIB) slice sectioning, after which transmission electron microscopy (TEM) imaging and diffraction pattern measurement have been performed.
3. The total layer thickness  $d_t$  of the TiO<sub>2</sub>/SiO<sub>2</sub> multilayer stack was measured at the centre point of each sample by ellipsometry.
4. Measurements at cross-sections near the centre point of batch reference samples using validated and calibrated preparation and measurement methods (SEM, TEM) were performed.
5. An overall statistical treatment was performed on the batch to determine the batch homogeneity of  $d_t$ .
6. The total uncertainty of  $d_t$  includes the following components: standard deviation of the mean batch value (52 samples), additional standard deviation from intra-sample inhomogeneity, and additional standard deviation from the model uncertainty. According to the certification report, this results in a total uncertainty for  $d_t$  of 24 nm.

***SHELF LIFE***

Provided the sample is stored and handled appropriately, the certification will remain valid for 24 months from the date of shipment.

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